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Line-ratio determination of atomic oxygen and $N_2(A \,{}^3\Sigma_u^+)$ metastable absolute densities in an RF nitrogen late afterglow

André Ricard¹, Soo-ghee Oh² and Vasco Guerra³

¹ Université de Toulouse, UPS, INPT, LAPLACE, 118 route de Narbonne, F-31062 Toulouse, France

² Division of Energy Systems Research, Ajou University, Suwon 443-749, Republic of Korea

³ Instituto de Plasmas e Fusão Nuclear, Instituto Superior Técnico, Universidade Técnica de Lisboa, 1049-001 Lisboa, Portugal

E-mail: vguerra@ist.utl.pt

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Abstract

Optical emission spectroscopy line-ratio methods are developed in order to estimate the absolute densities of nitrogen and oxygen atoms and metastable N₂(*A*) molecules in the nitrogen late afterglow of an RF discharge, operating at p = 8 Torr, Q = 1 slm and P = 100 W, in what constitutes an extension of the typical domain of application of these methods. [N] is obtained from the first positive (1⁺) emission with calibration by NO titration, [O] from the ratio of the NO_β to 1⁺ bands, and [N₂(*A*)] from the ratios of (i) the NO_γ and NO_β bands, (ii) the second positive (2⁺) and NO_β bands and (iii) the 1⁺ and 2⁺ bands. In addition to the determination of the N, O and N₂(*A*) absolute densities, the present investigation gives an indication on the order of magnitude of the rate coefficient of the very important reaction N₂(*X*, $v \ge 13$) + O \rightarrow NO + N at room temperature.

(Some figures may appear in colour only in the online journal)

1. Introduction

Gas discharges in pure nitrogen and in nitrogen-containing mixtures and their afterglows are interesting in very diversified fields, e.g. surface modification of materials [1–4], atmospheric plasma chemistry and investigation of the NO_x and O₃ formation and destruction mechanisms [5–9], or plasma sterilization [10–14]. Nitrogen's first electronically excited state, the metastable triplet N₂($A^{3}\Sigma_{u}^{+}$), has an energy threshold of about 6.2 eV and a lifetime ~2 s. Therefore, it is an important energy carrier and plays a relevant role in nitrogen discharges and afterglows, being involved in mechanisms as significant as ionization, dissociation, plasma chemistry and gas heating [15–21].

Optical emission spectroscopy is a very convenient plasma diagnostic, since it is relatively simple to perform and does not require very expensive equipment. Its use in the characterization of nitrogen plasmas is so vast that any references given would be merely indicative. The development of line-ratio or 'actinometric' methods, in particular, is spreading quickly [22–32]. They allow the diagnostics of various different quantities, such as the electron field, electron

density, electron temperature, electron energy distribution function and concentration of different species. Most of these diagnostics are used for active discharge conditions, where electron-impact excitation, dissociation and ionization have a central role. In this case, one may find conditions where the interpretation of the results is quite straightforward, for instance, if one species is predominantly created by direct electron impact and lost by radiative decay. However, the advent of more and more complete kinetic models has allowed one to refine the method and to address situations of growing complexity. A recent review of the evolution of line-ratio methods has been made by Zhu and Pu [31]. Clearly, the measurements remain relatively simple even in the more complex cases, although the interpretation becomes difficult and has to rely more and more on the accuracy of the underlying kinetic models.

The existence of rather complete and well-validated nitrogen kinetic models makes it possible to attempt the extension of line-ratio methods to study other conditions, already quite different from those for which they were initially developed. The purpose of this work is precisely to take a



Figure 1. A capacitive RF discharge is generated in a 6 mm i.d. and 30 cm long quartz tube. The flowing afterglow develops downstream in a tube of i.d. equal to 21 mm. An Ar–1.5%NO mixture can be injected after the discharge end (II) or after the early afterglow (III).

firm step in this direction, by investigating the nitrogen late afterglow, where electron processes are no longer present, and to attempt the estimation of metastable $N_2(A)$ molecules, a species that remains hard to measure in relatively simple experiments.

Our method requires the determination of the atomic nitrogen concentration and that of atomic oxygen impurities. The former is obtained from the intensity of the first positive (1⁺) emission at 580 nm with calibration by NO titration, while the latter is acquired from the ratio of NO_{β} to 1⁺ bands. N₂(*A*) is calculated using three independent line-ratio schemes, one involving the NO_{γ} and NO_{β} bands, a second one from the second positive (2⁺) and NO_{β} bands, and a third one from the 1⁺ and 2⁺ bands. It turns out that N₂(*A*) density derived by the first variant is inversely proportional to the N₂(*X*, *v*) + O \rightarrow NO + O reaction rate, subject to large uncertainties up to now. However, this apparent drawback can be turned into an advantage, as the present research can contribute to establish a value for this rate coefficient at room temperature.

The system under analysis is the late afterglow of an RF nitrogen discharge in a quartz tube of inner diameter 6 mm, operating at pressure p = 8 Torr, gas flow Q = 1 slm and power P = 100 W. The afterglow develops in a quartz tube with inner diameter 21 mm. The experiments were conducted using industrial nitrogen (1% impurity) and compared with pure nitrogen gas (10 ppm impurity) as far as [N] and [O] are concerned. Other results for the pink and late afterglow in pure nitrogen and in N₂–O₂ mixtures have been obtained in [33] for the same conditions.

The structure of the paper is as follows. In the next section we give a very brief description of the experimental setup. The results are presented in section 3, consisting of five subsections. The first is devoted to the determination of the nitrogen atomic concentration in the late afterglow; the second to the estimation of the oxygen atomic density; the third to the calculation of the N₂(*A*) density using the I_{γ}/I_{β} ratio; the fourth to the evaluation of the N₂(*A*) concentration from the I_{2^+}/I_{β} ratio; the final one to the determination of the N₂(*A*) concentration from the I_{1^+}/I_{2^+} ratio. Finally, the main results are summarized in section 4.

2. Experiment

The experimental setup has been previously described in [33] and is reproduced in figure 1. Basically, two quartz tubes of

inner diameter (i.d.) 21 mm are connected to a 6 mm i.d. tube, 30 cm long. The RF plasma is produced in the latter tube, using two rings separated by 2 cm. As depicted in figure 1, the RF discharge corresponds to the most upstream position. Moving downstream from this position three regions can be identified, namely, discharge, early afterglow and late afterglow.

The early or pink afterglow is characterized by a strong emission of the nitrogen first negative system. In this region vibrationally excited N₂($X^{1}\Sigma_{g}^{+}, v$) molecules play a significant role in the kinetics [34–36]. The late afterglow is dominated by N-atom three-body recombination, with subsequent emission from the nitrogen first positive system [37–40]. It corresponds to afterglow times ~50 ms.

Herein we focus on the late afterglow, where the measurements were performed. For the conditions studied, the most intense emissions were observed for a N₂ flow rate Q = 1 slm, pressure p = 8 Torr, and incident RF power at 13.56 MHz of 100 W. We carried out experiments using both a pure nitrogen gas (10 ppm impurity) and industrial nitrogen (1% impurity). The former gas is not used in the determination of N₂(A), as not all the emission bands required are visible.

Optical emission spectroscopy measurements were carried out with a Munera 500 optical spectrometer with 500 nm focal length and slits of 0.5 mm and a photomultiplier tube Hamamatsu R928. The nitrogen atomic concentration in the late afterglow was determined by NO titration [33, 37], with an Ar–1.5%NO gas mixture introduced downstream before the late afterglow, position (III) in figure 1. In addition, we have measured the emissions from the first and second positive systems of nitrogen, and from the NO_{β} and NO_{γ} bands, corresponding, respectively, to the transitions N₂($B \rightarrow A$), N₂($C \rightarrow B$), NO($B \rightarrow X$) and NO($A \rightarrow X$). Further details on the experimental setup can be found in [33].

3. Results and discussion

In this section we present three variants of a line-ratio method allowing the estimation of the $N_2(A)$ metastable density in the late afterglow. The procedure requires a previous estimation of the nitrogen and oxygen atomic concentrations. They can be obtained as well by optical emission spectroscopy, as detailed in sections 3.1 and 3.2. The evaluation of $[N_2(A)]$ is subsequently made in sections 3.3–3.5.

Before proceeding to these estimations, let us just recall that the measured relative intensity $I^m(\lambda_{ij})$ of a band at a certain wavelength λ_{ij} , resulting from the emission of a radiative state R_i^* decaying to a state *j*, is given by

$$I^{m}(\lambda_{ij}) = c(\lambda_{ij}) \frac{hc}{\lambda_{ij}} A_{ij}[R_i^*].$$
(1)

Here, $c(\lambda_{ij})$ is the spectral response of the spectrometer at the wavelength λ_{ij} corresponding to the $i \rightarrow j$ transition, h is Planck's constant, c is the value of the speed of light, A_{ij} is the Einstein coefficient for the transition, and $[R_i^*]$ is the density of the emitting radiative state.



Figure 2. Vibrational distribution function of the N₂($B^{3}\Pi_{g}$) state in the nitrogen early and late afterglows.

3.1. N-atom density

Figure 2 shows the relative vibrational distribution of the $N_2(B)$ state, $[N_2(B, v')]/[N_2(B, v = 0)]$ both in the early and in the late afterglows. Inspection of the figure reveals a modification in the dominant formation mechanisms of the $N_2(B^3\Pi_g)$ state. As is well known, the three-body recombination process predominantly populates the $N_2(B)$ state in the v = 11 level [37–39],

$$N + N + N_2 \rightarrow N_2(B, 11) + N_2.$$
 (R1)

The characteristic peak of the vibrational distribution function at v = 11 is thus a signature of reaction (R1). It is observed only in the late afterglow. Therefore, we can conclude that the N₂(*B*) state is primarily formed by reaction (R1) in this region. However, the overpopulation of level v = 11 is not visible in the early afterglow, where N₂(*B*) is significantly populated in collisions involving N₂(*A*) metastables and ground-state vibrationally excited molecules N₂(*X*, *v*) [34–36]. These states are subsequently quenched and are no longer available in the late afterglow. Such a qualitative interpretation was confirmed by preliminary modeling calculations for the conditions under investigation [41]. A refinement of the model and the detailed analysis of the simulation results will be performed in a future publication.

In order to estimate the nitrogen atomic density in the late afterglow, the expressive emission of the 11-7 band of the first positive system at 580 nm was measured, $N_2(B, v' = 11) \rightarrow N_2(A, v'' = 7) + hv(580 \text{ nm})$. This emission ensues the formation of N₂(B) in (R1). According to (1), the N₂(580 nm) band intensity is given by

$$I^{m}(580) = c(580) \frac{hc}{580 \,\mathrm{nm}} A_{580}[N_{2}(B, 11)].$$
(2)

We assume that a pseudo-stationary state is achieved for the concentration $[N_2(B,11)]$ in the late afterglow, resulting from a near equilibrium between its formation by reaction (R1) and its total destruction by radiative decay and quenching. *A priori*, possible $N_2(B, v = 11)$ loss terms are

$$N_2(B, v' = 11) \to N_2(A, v'') + hv,$$
 (R2)

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$$N_2(B) + N_2 \to N_2(A, X) + N_2,$$
 (R3)

$$N_2(B) + O_2 \to N_2 + O + O.$$
 (R4)

As we are accounting for the losses of $N_2(B, v = 11)$, reaction (R2) must include all possible v'' levels. The relevant rate coefficients are $k_1 \simeq 4.4 \times 10^{-34} \text{ cm}^6 \text{ s}^{-1}$ [34], $v_2 \simeq 2 \times 10^5 \text{ s}^{-1}$ [42,43], $k_3 \simeq 3 \times 10^{-11} \text{ cm}^3 \text{ s}^{-1}$ [34] and $k_4 \simeq 3 \times 10^{-10} \text{ cm}^3 \text{ s}^{-1}$ [44]. At p = 8 Torr and with an O₂ percentage below 1%, it is readily concluded that the dominant loss term is quenching with N₂, (R3).

From the creation-loss balance, and taking into account the evaluations above, we have

$$[\mathbf{N}_2(B, 11)] \simeq \frac{k_1[\mathbf{N}]^2[\mathbf{N}_2]}{k_3[\mathbf{N}_2]} = \frac{k_1}{k_3}[\mathbf{N}]^2.$$
(3)

The measured intensity I^m (580 nm) in the late afterglow can then be related to the N-atom density using (2),

6

$$a_{\rm N+N} I^m(580) \simeq k c(580) A_{580} \frac{k_1}{k_3} [{\rm N}]^2.$$
 (4)

In this expression, a_{N+N} is the fractional contribution of reaction (R1) to the total production of $N_2(B, v = 11)$ molecules, and k is a calibration factor to convert the relative $I^m(580)$ intensity into absolute values. The value of k is established by NO titration in the 2.1 i.d. tube, from the introduction of an Ar-1.5%NO gas mixture downstream before the late afterglow, position (III) in figure 1. Notice that it is only necessary to establish the calibration factor for one particular condition, as from that moment on it is enough to have the intensity $I^m(580)$ to deduce the absolute value [N] in any other situation. In turn, the factor a_{N+N} is determined as detailed in [33]. In practice it represents a mixing between the mechanisms of pure early and late afterglows, and should be equal to one if $N_2(B)$ is produced only through reaction (R1). We have obtained $a_{\rm N+N} \simeq 0.7$ and $a_{\rm N+N} \simeq 1$, respectively, for the cases of pure and industrial nitrogen. Finally, $A_{580} =$ $7.8 \times 10^4 \,\mathrm{s}^{-1}$ [42, 43].

Collecting all the information, the final result is an estimate for the nitrogen atomic concentration in the late afterglow, [N], at Q = 1 slm, p = 8 Torr and P = 100 W, of the order of 6.5×10^{14} cm⁻³ and 1.5×10^{15} cm⁻³, respectively, for pure and industrial nitrogen. A similar increase has been observed by other authors [45-48] and could be due to a change in the self-consistent electric field in the discharge as a consequence of the destruction of the $N_2(A, a')$ states by oxygen [44, 49]. Since these metastable states are involved in stepwise and associative/Penning ionization, direct ionization must compensate for the loss of these ionization channels. As such, the reduced electric field sustaining the discharge must increase. A modification in the N-atom surface recombination probability with small amounts of oxygen has also been suggested as a possible cause contributing to the increase in [N] with oxygen addition [50].

3.2. O-atom density

The presence of the NO_{β} bands in the late afterglow makes it possible to estimate the oxygen atomic density in this region,

because the emitting NO(B) state is formed in the three-body reaction involving O atoms

$$N + O + N_2 \rightarrow NO(B) + N_2.$$
 (R5)

We have followed the NO_{β} emission at 320 nm, corresponding to the NO(*B*, v' = 0) to NO(*X*, v'' = 8) transition, NO(*B*, v' = 0) \rightarrow NO(*X*, v'' = 8) + hv(320 nm). Possible NO(*B*) destruction mechanisms are

$$NO(B, v' = 0) \rightarrow NO(X, v'') + hv.$$
 (R6)

$$NO(B) + N_2 \rightarrow products,$$
 (R7)

$$NO(B) + O_2 \rightarrow products.$$
 (R8)

In the last two reactions, part of NO(*B*) may dissociate or be deactivated to excited NO(*A*) or to NO(*X*) [51]. The rate coefficients of processes (R5)–(R8) are approximately $k_5 \simeq 3.1 \times 10^{-34}$ cm⁶ s⁻¹ [12], $v_6 \simeq 4.7 \times 10^5$ s⁻¹ [42, 43], $k_7 \simeq 6.1 \times 10^{-13}$ cm³ s⁻¹ [52] and $k_8 \simeq 1.5 \times 10^{-11}$ cm³ s⁻¹ [52]. As the percentage of O₂ is always below 1%, the quenching of NO(*B*) by O₂, (R8), can be neglected as compared with the one by N₂, (R7).

The pseudo-stationary concentration of [NO(B)] in the late afterglow can be calculated, in consonance with the approximations already detailed, from

$$[NO(B)] \simeq \frac{k_5[N][O][N_2]}{\nu_6 + k_7[N_2]}.$$
(5)

Substituting [NO(*B*)] using (1)

$$I^{m}(320) \simeq c(320) \frac{hc}{320 \,\mathrm{nm}} A_{320} \frac{k_{5}[\mathrm{N}][\mathrm{O}][\mathrm{N}_{2}]}{\nu_{6} + k_{7}[\mathrm{N}_{2}]}, \qquad (6)$$

where $A_{320} \simeq 8.3 \times 10^4 \,\text{s}^{-1}$ [42] is the Einstein coefficient of the NO_{β}(0–8) transition. Finally, taking the ratio of the measured intensities of the 580 nm and the 320 nm lines, we obtain

$$a_{\rm N+N} \frac{I^m(580)}{I^m(320)} \simeq \frac{c(580)}{c(320)} \frac{580}{320} \frac{A_{580}}{A_{320}} \frac{(k_1/k_3)[{\rm N}]}{k_5[{\rm O}][{\rm N}_2]} (\nu_6 + [{\rm N}_2]k_7).$$
(7)

This equation provides the estimation of the oxygen atomic concentration if [N] and the spectral responses $c(\lambda)$ are known. The latter were measured with a calibrated W ribbon. For our spectrometer, we found c(320) = 1 a.u. and c(580) = 0.13 a.u.

We have now all the quantities required to estimate the atomic concentration [O] from equation (7). Using the previously determined N-atom concentration of $6.5 \times 10^{14} \text{ cm}^{-3}$ and $1.5 \times 10^{15} \text{ cm}^{-3}$ we obtain [O] $\simeq 9 \times 10^{12} \text{ cm}^{-3}$ and [O] $\simeq 7 \times 10^{14} \text{ cm}^{-3}$, respectively, for the pure and industrial nitrogen gases, i.e. impurity ratios [O]/[N₂] of about 35 ppm and 0.3%, respectively. Note that the value of 35 ppm deduced for the pure nitrogen gas implies that the observed oxygen is not coming exclusively from the feed gas, but also from micro-leaks in the reactor.



Figure 3. Emission of the NO_{γ} and NO_{β} bands in the late afterglow; industrial N₂ (99% purity), 1 slm, 8 Torr and 100 W.

3.3. $N_2(A)$ density from the I_{γ}/I_{β} ratio

As the densities [N] and [O] have already been obtained, it is now possible to use optical emission spectroscopy to estimate the density of $N_2(A)$ metastables in the late afterglow and for the industrial nitrogen case, where all the NO bands are clearly visible. We do so using three different line ratios. The first one is the ratio of the NO_{ν} emission at 259 nm, corresponding to the transition NO(A, v' = 0) \rightarrow NO(X, v'' = 3) + hv(259 nm), to the NO_{β} emission at 262 nm, due to the NO(B, $v' = 0) \rightarrow$ NO(X, v'' = 4) + hv(262 nm) transition. The second one is the ratio of the nitrogen 2⁺ system at 316 nm, $N_2(C, v' =$ 1) $\rightarrow N_2(B, v'' = 0) + hv(316 \text{ nm})$ to the NO_{\beta} band at 320 nm already used in the determination of the oxygen atomic density. The choice of transitions with neighboring wavelengths for the line ratios has the small advantages of narrowing the wavelength range to scan and making it possible to neglect any variation of the spectral response $c(\lambda)$ (see expression (1)). We will additionally determine $[N_2(A)]$ from the ratio of the 1^+ band at 580 nm to the 2^+ one at 316 nm. For now we discuss the I_{γ}/I_{β} procedure, whereas the remaining ones are presented in the subsequent sections.

The emission spectrum showing the NO γ ($\lambda < 260$ nm) and NO $_{\beta}$ ($\lambda > 260$ nm) bands in the late afterglow (after position III in figure 1) is given in figure 3, for the case of industrial N₂ (99% purity) and without external Ar–1.5%NO addition. Therefore, the emissions of the NO $_{\gamma}$ and NO $_{\beta}$ bands observed in this figure are only a result of the O and NO impurities in the industrial N₂ gas.

The variation of the intensities of the bands at 259 and 262 nm in the late afterglow as a function of the Ar–1.5%NO introduced in the late afterglow is represented in figure 4, for the industrial nitrogen gas. As can be seen, the intensities $I^m(259)$ and $I^m(262)$ are nearly the same up to 350 sccm of Ar–1.5%NO, where the extinction point is observed. The latter condition is at the basis of the NO titration method and allows the determination of the N-atom density [33, 37].

The intensity of the NO_{β} band $I^m(262)$ is given similarly by equation (6). In turn, the observed intensity of the NO_{γ}



Figure 4. Intensities of the $NO_{\gamma}(259 \text{ nm})$ and $NO_{\beta}(262 \text{ nm})$ bands in the late afterglow; industrial N_2 (99% purity), 1 slm, 8 Torr and 100 W.

band $I^m(259)$ can be explained by the three reactions

$$N_2(A) + NO \rightarrow N_2(X) + NO(A), \tag{R9}$$

$$NO(A) \rightarrow NO(X) + h\nu$$
, (R10)

 $NO(A) + N_2 \rightarrow products,$ (R11)

where NO in reaction (R9) is coming essentially from the NO added into the late afterglow as part of the titration procedure. The corresponding rate coefficients are $k_9 = 6.6 \times 10^{-11} \text{ cm}^3 \text{ s}^{-1}$ [44], $v_{10} = 5 \times 10^6 \text{ s}^{-1}$ [52] and $k_{11} = 10^{-13} \text{ cm}^3 \text{ s}^{-1}$ [52]. Hence, we can write

$$I^{m}(259) = c(259) \frac{hc}{259 \text{ nm}} A_{259}[\text{NO}(A)]$$

$$\simeq c(259) \frac{hc}{259 \text{ nm}} A_{259} \frac{k_{9}[\text{N}_{2}(A)][\text{NO}]}{\nu_{10} + k_{11}[\text{N}_{2}]}.$$
(8)

The ratio of the intensities of the NO_{γ} and NO_{β} bands, given by expressions (8) and (6) (with 320 nm replaced by 262 nm), can be written as

$$\frac{I^m(259)}{I^m(262)} \simeq \frac{A_{259}}{A_{262}} \frac{k_9 [N_2(A)] [NO]}{k_5 [N] [O] [N_2]} \frac{\nu_6 + k_7 [N_2]}{\nu_{10} + k_{11} [N_2]}, \qquad (9)$$

where we have neglected the variations in the spectral responses $c(\lambda)$ between 259 and 262 nm, and have approximated $262/259 \simeq 1$, $A_{259} = 7.7 \times 10^5 \text{ s}^{-1}$ and $A_{262} = 2.4 \times 10^4 \text{ s}^{-1}$ [42, 43].

In order to use equation (9), we still need to estimate the ratio [NO]/[O]. The atomic oxygen concentration determined in section 3.2 cannot be used here, as the introduction of NO will change its value. A simplified kinetics of atomic oxygen in the late afterglow can be described by

$$N + NO \rightarrow N_2 + O, \tag{R12}$$

$$N_2(A) + O \rightarrow NO + N(^2D), \qquad (R13)$$

$$N_2(X, v \ge 13) + O \rightarrow NO + N,$$
 (R14)

$$N + O + N_2 \rightarrow NO(X) + N_2. \tag{R15}$$

The pseudo-stationary density [O] can then be obtained from l_{1} [D][D] c_{1} (1) [D] c_{2} (1) [D] c

$$k_{12}[\mathbf{N}][\mathbf{NO}] \simeq (k_{15}[\mathbf{N}][\mathbf{N}_{2}] + k_{13}[\mathbf{N}_{2}(A)] + k_{14}[\mathbf{N}_{2}(X, v \ge 13)])[\mathbf{O}].$$
(10)

Therefore, the required [NO]/[O] ratio is given by

$$\frac{[\text{NO}]}{[\text{O}]} \simeq \frac{k_{15}[\text{N}][\text{N}_2] + k_{13}[\text{N}_2(A)] + k_{14}[\text{N}_2(X, v \ge 13)]}{k_{12}[\text{N}]}.$$
(11)

The rate coefficients of processes (R12) and (R13) are $k_{12} = 1.8 \times 10^{-11}$ [44] and $k_{13} = 7 \times 10^{-12} \text{ cm}^3 \text{ s}^{-1}$. Regarding reaction (R14), there are large uncertainties in the value of its coefficient. As the reaction is exothermic for $v \ge 13$, it is expected that the rate coefficient strongly increases for $v \leq 13$, exhibiting a smoother rise for v > 13. In previous modeling studies, simple step functions in the range 10^{-13} - $10^{-11} \text{ cm}^3 \text{ s}^{-1}$ have been used [44, 49]. Bose and Candler present a quasiclassical trajectory (OCT) calculation of this rate [53], but they only calculate data for high temperatures. For instance, for rotational equilibrium with a rotational temperature equal to the gas temperature, T = 7000 K, they report values of $8 \times 10^{-12} \text{ cm}^3 \text{ s}^{-1}$, $2.6 \times 10^{-11} \text{ cm}^3 \text{ s}^{-1}$ and $5 \times 10^{-11} \text{ cm}^3 \text{ s}^{-1}$, respectively, for v = 10, 15 and 20. However, extrapolation of these values to lower temperatures is far from trivial. In order to try to address this question, calculations of these rate coefficients using the forced harmonic oscillator model [54-57] will be performed in the future. However, theoretical calculations by Macheret and co-workers [58, 59] foresee that the actual reaction paths are different at low temperatures (T < 2000 K) and high temperatures (T > 2000 K). In the former case, an electronically nonadiabatic curve-crossing mechanism is favored, involving multiquantum vibrational transitions at the intersection of the electronic terms of the N2-O system and the formation of the intermediate long-lived complex $N_2O(X^{1}\Sigma^{+})$. The calculated probabilities for the non-adiabatic reaction for $T \leq 1000 \,\mathrm{K}$ are in the range 10^{-2} – 10^{-3} , translating into a pre-exponential factor of 10^{-13} – 10^{-12} cm³ s⁻¹ for a vibrational temperature of the lower v-levels $T_{\rm V} \simeq 3000 \, {\rm K}$ [59]. Note that the electronically adiabatic channel would have a rate coefficient at room temperature orders of magnitude lower [59]. Due to the lack of data, for the moment we will consider $k_{14} = 10^{-13}$ - 10^{-11} cm³ s⁻¹. Finally, the rate coefficient of reaction (R15) is $k_{15} = 10^{-32} \text{ cm}^6 \text{ s}^{-1}$, 32 times higher than the partial rate for NO(B) production in process (R5).

It is relatively easy to show that, for the present conditions, the dominant loss frequency in equation (11) is due to reaction (R14). Using $[N] \simeq 1.5 \times 10^{15} \text{ cm}^{-3}$, as concluded in section 3.1, the loss frequency of reaction (R15) is $k_{15}[N][N_2] \sim 4 \text{ s}^{-1}$. Next, for relative N₂(*A*) densities below 5×10^{-5} , as is typical for nitrogen afterglows in this range of pressure [36], the loss term in process (R13) is $k_{13}[N_2(A)] < 90 \text{ s}^{-1}$. Finally, to estimate the atomic oxygen losses in the NO formation mechanism (R14) we assume that $[N_2(X, v \ge 13)] \sim 5 \times 10^{-3}[N_2]$ [60], so that $k_{14}[N_2(X, v \ge$ $13)] \sim 1.2 \times (10^2 - 10^4) \text{ s}^{-1}$, depending on the value of k_{14} . In passing, let us note that the atomic oxygen losses at the wall occur at a frequency of about 1 s^{-1} for a wall recombination probability γ_0 of the order of 10^{-4} [61, 62], or 10 times higher for $\gamma_0 \sim 10^{-3}$ [63, 64], so they can be neglected as well in the present evaluation.

In this way, equation (11) can be approximated by

$$\frac{[\text{NO}]}{[\text{O}]} \simeq \frac{k_{14}[\text{N}_2(x, v \ge 13)]}{k_{12}[\text{N}]}.$$
 (12)

Substituting in (9),

 $\frac{I^{m}(259)}{I^{m}(262)} \simeq \frac{A_{259}}{A_{262}} \frac{k_9[N_2(A)]}{k_5[N][N_2]} \frac{\nu_6 + k_7[N_2]}{\nu_{10} + k_{11}[N_2]} \frac{k_{14}[N_2(x, v \ge 13)]}{k_{12}[N]}.$ (13)

Apart from the uncertainties surrounding the coefficient k_{14} , the only unknown in this expression is the concentration $[N_2(A)]$. Thus, the density of this metastable state in the afterglow can be estimated by the line ratio $I^m(259)/I^m(262)$.

From figure 4, for the industrial N₂ gas $I^m(259)/I^m(262) = 1.2$ when the introduced NO in the late afterglow approaches zero. Substituting all the values in equation (13), the final result for the N₂(A) concentration in the late afterglow [N₂(A)] $\simeq 1.1 \times 10^9 - 1.1 \times 10^{11} \text{ cm}^{-3}$, as k_{14} decreases from 10^{-11} to $10^{-13} \text{ cm}^3 \text{ s}^{-1}$.

It is worth noting that with the pure nitrogen gas a mixed late and pink afterglow ($a_{N+N} = 0.7$) was observed. That being so, in that case N₂(A) metastables may be partially formed in reactions involving vibrationally excited molecules N₂(X, v) as in the pink afterglow [36, 60]. In contrast, the nearly identical variations of the NO_{γ} and NO_{β} bands detected in figure 3 suggest that for industrial nitrogen N₂(A) molecules are following the nitrogen atoms. This means they are mainly produced as a result of three-body N recombination, either directly or via a formation of the N₂(B) state and subsequent quenching to N₂(A).

3.4. $N_2(A)$ density from the I_{2^+}/I_β ratio

Another possibility to estimate the N₂(A) metastable density in the late afterglow is given by the line ratio of the 2⁺ system at 316 nm, N₂(C, 1–B, 0) with the NO_{β}(0–8) band at 320 nm. The dominant reactions responsible for the 2⁺ emission in the late afterglow are

$$N_2(A) + N_2(A) \rightarrow N_2(C, 1) + N_2,$$
 (R16)

$$N_2(C, 1) \to N_2(B) + h\nu, \qquad (R17)$$

$$N_2(C, 1) + N_2 \rightarrow \text{products.}$$
 (R18)

The rate coefficient of reaction (R16) is $k_{16} = 4.1 \times 10^{-11} \text{ cm}^3 \text{ s}^{-1}$ [65], where it was assumed that most of the N₂(*A*) molecules are in the ground vibrational level. The loss rates of N₂(*C*, v' = 1) molecules are given by $v_{17} = 2.7 \times 10^7 \text{ s}^{-1}$ [42, 43] and $k_{18} = 3 \times 10^{-11} \text{ cm}^3 \text{ s}^{-1}$ [66, 67].

In accordance with mechanisms (R16)-(R18), we can write

$$I^{m}(316) = c(316) \frac{hc}{316 \text{ nm}} A_{316}[N_{2}(C)]$$

$$\simeq c(316) \frac{hc}{316 \text{ nm}} A_{316} \frac{k_{16}[N_{2}(A)]^{2}}{\nu_{17} + k_{18}[N_{2}]},$$
(14)

where $A_{316} = 1.3 \times 10^7 \,\text{s}^{-1}$ [42, 43]. Using (6) we finally obtain

$$\frac{I^{m}(320)}{I^{m}(316)} \simeq \frac{A_{320}}{A_{316}} \frac{k_{5}[N][O][N_{2}]}{k_{16}[N_{2}(A)]^{2}} \frac{\nu_{17} + k_{18}[N_{2}]}{\nu_{6} + k_{7}[N_{2}]}.$$
 (15)

The concentration of $N_2(A)$ metastables can be determined from (15). For the industrial nitrogen gas the measured $I^m(320)/I^m(316)$ ratio is 13, from which it follows that $[N_2(A)] \sim 2.4 \times 10^{11} \text{ cm}^3 \text{ s}^{-1}$.

3.5. $N_2(A)$ density from the I_{1^+}/I_{2^+} ratio

One last easy estimation of $N_2(A)$ can still be made, making use of bands already analyzed. As a matter of fact, the ratio of the 1⁺ emission at 580 nm, given by (2) and (3), to the 2⁺ emission at 316 nm, expressed in (14), is

$$\frac{I^{m}(580)}{I^{m}(316)} \simeq \frac{c(580)}{c(316)} \frac{A_{580}}{A_{316}} \frac{316}{580} \frac{k_{1}[N]^{2}}{k_{3}k_{15}[N_{2}(A)]^{2}} (\nu_{16} + k_{17}[N_{2}]).$$
(16)

The experimental ratio is 2.24, leading to the result $[N_2(A)] \sim 7.3 \times 10^{10} \text{ cm}^3 \text{ s}^{-1}$.

4. Conclusions

In this work we have shown that optical emission spectroscopy line-ratio methods are extremely powerful and can be extended far beyond their typical domain of application. In particular, we have developed a procedure to obtain the absolute densities of N and O atoms and $N_2(A)$ metastable molecules in the nitrogen late afterglow. An RF discharge was generated at p = 8 Torr, P = 100 W, Q = 1 slm, in a quartz tube of inner diameter 6 mm, whereas the afterglow developed in a quartz tube of i.d. 21 mm. The experiments were conducted using both pure nitrogen (10 ppm impurity) and industrial nitrogen (1% impurity). However, due to the difficulty in the detection of all the NO bands, the $N_2(A)$ concentration was derived only for the case of industrial nitrogen.

The nitrogen atomic density in the late afterglow was determined from the emission of the 1⁺ nitrogen system $N_2(11 - 7)$ at 580 nm, while the oxygen atomic density was derived from the ratio of the $NO_\beta(0-8)$ band at 320 nm to the 580 nm line. The $N_2(A)$ metastable concentration was estimated using three different line-ratios, the ratio of the $NO_\gamma(0-3)$ band at 259 nm to the $NO_\beta(0-4)$ band at 262 nm, the ratio of the N_2 2⁺ band (1–0) at 316 nm to the 320 nm band, and the ratio of the previously used 1⁺ 580 nm and 2⁺ 316 nm bands. The results are summarized in table 1. Note that the uncertainties indicated in the table refer only to the experimental errors. As such, they do not include the influence of any doubts surrounding the reaction rate coefficients nor of the pseudo-stationary approach inherent in the method.

The three methods to determine the N₂(*A*) concentration lead to rather consistent results, pointing to a value of the order of ~10¹¹ cm⁻³. One possible reason for the slightly higher value deduced from the I_{γ}/I_{β} and I_{2^+}/I_{β} ratios could be the contribution of reaction (R8) and/or of the similar reaction involving NO, NO(*B*) + NO \rightarrow products already competitive

Table 1. Absolute densities in cm⁻³ estimated in the late afterglow: p = 8 Torr, Q = 1 slm, P = 100 W.

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Species	Lines	Pure N ₂	Industrial N ₂	Uncertainty
[N]	$I_{1^+}(580)$	6×10^{14}	1.5×10^{15}	30%
[0]	$I_{\beta}(320)/I_{1^+}(580)$	9×10^{12}	7×10^{14}	50%
$[N_2(A)]$	$I_{\gamma}(259)/I_{\beta}(262)$		$1.1 \times (10^9 - 10^{11})$	70%
$[N_2(A)]$	$I_{2^+}(316)/I_{\beta}(320)$	—	2.4×10^{11}	45%
$[N_2(A)]$	$I_{1^+}(580)/I_{2^+}(316)$	—	7.3×10^{10}	35%

with that of (R7). Note that $k_7 = 6.1 \times 10^{-13} \text{ cm}^3 \text{ s}^{-1}$, $k_8 = 1.5 \times 10^{-11} \text{ cm}^3 \text{ s}^{-1}$, while $k_{\text{NO}} = 2 \times 10^{-10} \text{ cm}^3 \text{ s}^{-1}$ [52]. This would imply a correction in the denominator of expression (15), to be read $v_6 + k_7 [N_2] + k_8 [O_2] + k_{\text{NO}} [\text{NO}]$, with the consequent decrease in the estimated value for $[N_2(A)]$.

The range of possible values for $[N_2(A)]$ calculated from the $I_{\nu}(259)/I_{\beta}(262)$ ratio correspond to the uncertainty in the rate coefficient of the NO formation reaction $N_2(X, v \ge$ 13) + O \rightarrow NO+N, k_{14} , between 10⁻¹³ and 10⁻¹¹ cm³ s⁻¹, the lower value of the rate coefficient corresponding to the higher $N_2(A)$ density. Comparison with the result obtained from the $I_{2^+}(316)/I_{\beta}(320)$ ratio suggests a rate coefficient close to 10^{-13} cm³ s⁻¹. However, preliminary model calculations [41] for the conditions and measurements presented in [33] would suggest instead a value of 10^{-11} cm³ s⁻¹ and/or a higher deactivation of vibrationally excited molecules $N_2(X, v)$ by O atoms than normally considered [44, 49]. Hence, the present results point toward a value for k_{14} of the order of 10^{-13} cm³ s⁻¹ and a stronger deactivation of intermediate and high $N_2(X, v)$ vibrational levels by oxygen atoms than previously proposed. This finding is consistent with the mechanisms and theoretical predictions from [58, 59]. The development of a complete self-consistent model to further investigate and clarify these questions from the comparison of the simulation predictions with the present results and those of Kang et al [33] is under way and will be presented in a forthcoming publication.

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